



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	<i>Baer et al.</i>)	Group No.:	1763
Serial No.:	10/675,697)	Examiner:	Arancibia
Filed:	09/30/2003)	Docket No.:	HSJ9-2003-0032US1

For: "METHOD OF FORMING A READ SENSOR USING PHOTORESIST
STRUCTURES WITHOUT UNDERCUTS WHICH ARE REMOVED
USING CHEMICAL-MECHANICAL POLISHING (CMP) LIFT-OFF
PROCESSES"

MAIL STOP AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Entered with RCE
9/26/5
MW 9/29/5

Sir:

REQUEST FOR RECONSIDERATION

The Applicant respectfully submits this Request for Reconsideration in response to the Office Action mailed on 23 May 2005 from Examiner Maureen Gramaglia Arancibia.